

VERIFICATION OF A TRANSLATION

I, the below named Translator, hereby declare that;

I am the translator of the Japanese specification of
U.S. Patent Application under Title of the Invention
" ELECTRON BEAM APPARATUS AND METHOD OF MANUFACTURING
SEMICONDUCTOR DEVICE USING THE APPARATUS " filed on the 2nd
day of November, 2001.


That I believe the attached English translation is a
true and complete translation of said application as filed.

I hereby declare that all statements made herein of my
own knowledge are true and that all statements made on
information and belief are believed to be true; and further
that these statements were made with the knowledge that
willful false statements and the like so made are punishable
by fine or imprisonment, or both, under Section 1001 of Title
18 of the United States Code and that such willful false
statements may jeopardize the validity of the application or
any patent issued thereon.

Dated this 27th day of February, 2002

Full name of the Declarant: Sumie OHTSUKA

Signature of the Declarant:

A handwritten signature in cursive script, appearing to read 'S. Ohtsuka', written over a horizontal line.

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